

**AMENDMENT UNDER 37 C.F.R. § 1.116  
EXPEDITING PROCEDURE  
EXAMINING GROUP 1700**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

|             |  |             |                     |
|-------------|--|-------------|---------------------|
| Applicant:  | Wunnicke, <i>et al.</i>  | Docket No.: | 2004 SP 00138 US    |
| Serial No.: | 10/781,920   | Art Unit:   | 1756                |
| Filed:      | February 20, 2004  | Examiner:   | Brittany L. Raymond |
| For:        | Method for Fabricating a Resist Mask for Patterning Semiconductor Substrates |             |                     |

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT UNDER 37 CFR § 1.116**

Dear Sir:

Applicant respectfully submits the following amendments and remarks in response to Examiner's Office Action dated April 13, 2007, which Action is made final. Applicant respectfully requests that these amendments and remarks be entered in pursuant to the provisions of 37 CFR § 1.116, and respectfully request reconsideration of claims 1-5 and 9-22.